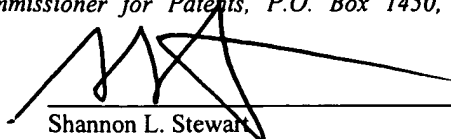




PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on October 23, 2008.


Shannon L. Stewart

Appl No. : 10/593,857 Confirmation No. 5813
Applicant : Kim, Nam Hun
Filed : September 22, 2006
Title : PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND
METHOD FOR ETCHING THE WAFER USING THE SAME
TC/A.U. : 1792
Examiner : Duy Vu Nguyen Deo
Docket No. : 58409/N305
Customer No. : 23363

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Post Office Box 7068
Pasadena, CA 91109-7068
October 23, 2008

Commissioner:

In response to the Office action of June 23, 2008, please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.